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#### Contract

# Supply of a Plasma Etch Tool for Silicon Carbide (SiC) Etching

Swansea University

F03: Contract award notice

Notice identifier: 2021/S 000-014061

Procurement identifier (OCID): ocds-h6vhtk-029388

Published 21 June 2021, 3:15pm

# **Section I: Contracting authority**

## I.1) Name and addresses

Swansea University

Procurement - VC's Office, Swansea University, Singleton Park

Swansea

SA28PP

#### **Email**

procurement@swansea.ac.uk

## **Telephone**

+44 1792602779

#### Country

**United Kingdom** 

#### **NUTS** code

UKL18 - Swansea

#### Internet address(es)

Main address

www.swansea.ac.uk

Buyer's address

https://www.sell2wales.gov.wales/search/Search AuthProfile.aspx?ID=AA0345

## I.2) Information about joint procurement

The contract is awarded by a central purchasing body

## I.4) Type of the contracting authority

Body governed by public law

## I.5) Main activity

Education

# **Section II: Object**

## II.1) Scope of the procurement

## II.1.1) Title

Supply of a Plasma Etch Tool for Silicon Carbide (SiC) Etching

Reference number

SU111(21)

#### II.1.2) Main CPV code

• 38000000 - Laboratory, optical and precision equipments (excl. glasses)

#### II.1.3) Type of contract

**Supplies** 

#### II.1.4) Short description

This Tender Specification is for the supply and delivery of a Plasma Etch Tool for SiC etching. In procuring this system, the University is seeking to augment its well-established existing plasma etch and deposition tool set, expanding the capabilities that the CISM will be able to provide.

The new tool will be of strategic importance in delivering both frontside SiC etch capability for power MOSFET trench applications, and backside SiC via etch capability for GaN-on-SiC device applications. Reliability of the equipment is therefore paramount to maintaining, supporting and complimenting the wide array of experimental work that will be conducted within the facility.

#### II.1.6) Information about lots

This contract is divided into lots: No

#### II.1.7) Total value of the procurement (excluding VAT)

Lowest offer: £644,000 / Highest offer: £723,000 taken into consideration

## II.2) Description

## II.2.2) Additional CPV code(s)

- 38900000 Miscellaneous evaluation or testing instruments
- 38970000 Research, testing and scientific technical simulator
- 39180000 Laboratory furniture

## II.2.3) Place of performance

**NUTS** codes

• UKL - Wales

Main site or place of performance

to be delivered to Newport Wafer Fab

#### II.2.4) Description of the procurement

This Tender Specification is for the supply and delivery of a Plasma Etch Tool for SiC etching. In procuring this system, the University is seeking to augment its well-established existing plasma etch and deposition tool set, expanding the capabilities that the CISM will be able to provide.

The new tool will be of strategic importance in delivering both frontside SiC etch capability for power MOSFET trench applications, and backside SiC via etch capability for GaN-on-SiC device applications. Reliability of the equipment is therefore paramount to maintaining, supporting and complimenting the wide array of experimental work that will be conducted within the facility.

#### II.2.5) Award criteria

Quality criterion - Name: Technical / Weighting: 45

Quality criterion - Name: After Sales Support & Warranty / Weighting: 15

Quality criterion - Name: Lead Time / Weighting: 10

Price - Weighting: 30

#### II.2.11) Information about options

Options: No

### II.2.13) Information about European Union Funds

The procurement is related to a project and/or programme financed by European Union funds: No

## II.2.14) Additional information

Funding for this procurement has been secured from the Driving the Electric Revolution (DER) Industrialisation Centres Programme via Innovate UK.

## **Section IV. Procedure**

## **IV.1) Description**

## IV.1.1) Type of procedure

Open procedure

#### IV.1.8) Information about the Government Procurement Agreement (GPA)

The procurement is covered by the Government Procurement Agreement: Yes

## IV.2) Administrative information

#### IV.2.1) Previous publication concerning this procedure

Notice number: 2021/S 000-003105

## Section V. Award of contract

#### **Contract No**

SU111(21)

A contract/lot is awarded: Yes

## V.2) Award of contract

## V.2.1) Date of conclusion of the contract

17 May 2021

## V.2.2) Information about tenders

Number of tenders received: 2

Number of tenders received from SMEs: 0

Number of tenders received from tenderers from other EU Member States: 2

Number of tenders received from tenderers from non-EU Member States: 0

Number of tenders received by electronic means: 2

The contract has been awarded to a group of economic operators: No

# V.2.3) Name and address of the contractor

SPTS Technologies

Ringland Way

Newport

**NP18 2TA** 

Country

**United Kingdom** 

NUTS code

• UKL21 - Monmouthshire and Newport

The contractor is an SME

Yes

# V.2.4) Information on value of contract/lot (excluding VAT)

Lowest offer: £644,000 / Highest offer: £723,000 taken into consideration

# Section VI. Complementary information

# VI.3) Additional information

(WA Ref:111656)

# VI.4) Procedures for review

# VI.4.1) Review body

High Court

Royal Courts of Justice, The Strand

London

WC2A 2LL

Telephone

+44 2079477501

Country

**United Kingdom**